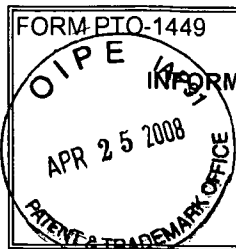


FORM PTO-1449 	ATTY. DOCKET <b>033082 M 343</b>	SERIAL NO. <b>10/591,476</b>
	APPLICANT: <b>Yasuhiko KOJIMA</b>	
	FILING DATE <b>September 1, 2006</b>	GROUP ART UNIT <b>1751</b>

## U.S. PATENT DOCUMENTS

*Examiner's Initials		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE, IF APPROPRIATE
	AA	3,198,167	August 3, 1965	R. Bakish et al.			
	AB	4,321,073	March 23, 1982	Blair			
	AC						
	AD						
	AE						
	AF						
	AG						

## FOREIGN PATENT DOCUMENTS

*Examiner's Initials		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION YES NO	
	AH	2005/058789	6/30/2005	WO				
	AI							
	AJ							
	AK							
	AL							
	AM							
	AN							
	AO							
	AP							

## OTHER INFORMATION (Including Author, Title, Date, Pertinent Pages, Etc.)

	AQ	Supplementary European Search Report (Application No. EP 04 74 6795)
	AR	MOUCHE M-J et al., "Metal-organic chemical vapor deposition of copper.....precursor", THIN SOLID FILMS, ELSEVIER-SEQUOIA S.A. LAUSANNE, CH, vol. 262, 1995, pages 1-6, XP002347082, ISSN: 0040-6090
	AS	

EXAMINER:

/Mandy Louie/

DATE CONSIDERED:

10/13/2009

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.